

Title (en)

METHOD AND DEVICE FOR ADJUSTING VAPOUR PRESSURES WITH HIGH ACCURACY IN THE PRODUCTION OF GAS MIXTURES BY EVAPORATION OF ONE OR MORE LIQUIDS TO BE EVAPORATED

Title (de)

VERFAHREN UND VORRICHTUNG ZUR HOCHGENAUEN EINSTELLUNG VON DAMPFDRÜCKEN BEI DER HERSTELLUNG VON GASGEMISCHEN MITTELS VERDUNSTUNG EINER ODER MEHRERER ZU VERDUNSTENDEN FLÜSSIGKEIT

Title (fr)

PROCÉDÉ ET DISPOSITIF POUR LE RÉGLAGE TRÈS PRÉCIS DE PRESSIONS DE VAPEUR LORS DE LA FABRICATION DE MÉLANGES GAZEUX PAR ÉVAPORATION D'UN OU PLUSIEURS LIQUIDES À ÉVAPORER

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Designated contracting state (EPC)

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